Special Issue

New Trends in Manufacturing Metrology

Message from the Guest Editors

Manufacturing metrology is strictly bound to developments in the industrial sector. Discoveries in the field of theoretical physics and materials science result in the emergence of new manufacturing techniques, pushing forward the existing possibilities of industrial production. One of the main challenges in this field, which is the condition of its further development, is the problem of finding appropriate methods and tools for effective assessment of the quality of manufactured products. We invite contributions to this Special Issue on topics including, but not limited to, the following areas:

- Metrology systems integrated into manufacturing tools and lines
- Optical metrology in manufacturing
- Traceability of manufacturing metrology systems

Guest Editors

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Deadline for manuscript submissions

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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

Editor-in-Chief

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